Standard Operating Procedures for 2D-CVD System

updated on August 19, 2020 by Chun-Li Lo



Status before operating:

- 1. Quartz tube is at vacuum (maybe not base vacuum, but certainly not at atmospheric pressure)
- 2. Furnace is at room temperature (or < 40 °C)
- 3. All Solenoid Valves (valves 1 through 7) are closed
- 4. Vacuum pump (in the chase) is turned off

Before running process:

- 1. Enable the system on iLab ("2D-CVD" under furnace core)
- 2. Turn on vacuum pump with the switch (in the chase)
- 3. Wear solvent gloves. Loosen the ultratorr fitting clockwise about 1-2 turns (no need to fully loosen it all the way)
- 4. Turn on Switch 3 (N2 Purge) to backfill the tube.

- 5. Have your hands on the ultratorr fitting to "feel" it push off the end of the tube. Then, set it aside.
- 6. Turn off Switch 3 (N2 Purge)
- 7. Wear acid gloves. Manipulate your sample pull out boat / put on sample / push in boat
- 8. Take off acid gloves. Reinstall the ultratorr fitting to the quartz tube, and snug down the fitting. Finger tight (counterclockwise) is fine.
- 9. Turn on Switch 1 (Slow Pump)
- 10. Wait for tube to pump down to below <u>1000 mT</u> with the Pirani gauge.
- 11. Turn off Switch 1 (Slow Pump)
- 12. Turn on Switch 2 (Fast Pump)
- 13. Watch to make sure the pressure continues to go down
- 14. Turn on Switch 3 (N2 Purge) for 5 or 10 seconds, then turn it off
 - a. This purges the tube with N2: Pressure will rise to about <u>35 Torr</u> with the N2 on, and then return to base pressure once N2 is off. Wait for the pressure to return to <u>100 mT</u> or less before you continue.
 - b. Note: For the reading of the "35 Torr," use the display on Throttle Valve Controller to read if Pirani Gauge is not working.
- 15. Repeat this purge sequence for 10 times.
 - a. At the end of the purge sequence, Switch 3 (N2 Purge) should be off, and Switch 2 (Fast Pump) should be ON.
- 16. Record the base pressure. Should be around 5-20 mTorr.

Running process:

- 1. Ramp up temperatures on the furnace controller. Set temperatures on each of the 3 temp controllers and wait for the temperature to reach the set value.
- 2. Turn on Switch 5 (Ar process); turn on Ar on MFC Controller. Adjust flow rate of Ar and record the pressure.
- 3. Turn on Switch 7 (H₂S process); turn on H₂S on MFC Controller. Adjust flow rate of H₂S and record the pressure.
- 4. Wait for 5 minutes to stabilize flow rates.
- 5. Turn on plasma.
- 6. Increase plasma power slowly (~ 10 W /10 sec) until reaching the targeted power.
- 7. <u>Main process</u>: wait for required process time. Check the stability of plasma often.
- 8. Decrease plasma power to 0 W.
- 9. Turn off plasma
- 10. Turn off H_2S on MFC Controller. Then, turn off Switch 7 (H_2S process).
- 11. Turn off Ar on MFC Controller. Then, turn off Switch 5 (Ar process).
- 12. Turn down temperature of the furnace to 0 $^{\circ}\mathrm{C}.$
- 13. Record the base pressure. Should be around 5-20 mTorr.
- 14. Disable the system on iLab.
- 15. Wait until the furnace reach room temperature before unloading the sample (takes ~8-10 hours). Fast pump can be either on or off during furnace cooling.

After running process (sample unloading & tube cleaning):

1. Make sure the temperature is below 40 $^{\circ}\mathrm{C}$ before unloading.

- 2. Enable the system on iLab.
- 3. If pump is off, do the following steps (a-e). Otherwise, do step 4.
 - a. Turn on vacuum pump with the switch (in the chase).
 - b. This Turn on Switch 1 (Slow Pump).
 - c. Wait for tube to pump down to below <u>1000 mT</u> with the Pirani gauge.
 - d. Turn off Switch 1 (Slow Pump).
 - e. Turn on Switch 2 (Fast Pump).
- 4. Turn on Switch 3 (N2 Purge) for 5 or 10 seconds, then turn it off
 - a. This purges the tube with N2: Pressure will rise to about <u>35 Torr</u> with the N2 on, and then return to base pressure once N2 is off. Wait for the pressure to return to <u>100 mT</u> or less before you continue.
 - b. Note: For the reading of the "35 Torr," use the display on Throttle Valve Controller to read if Pirani Gauge is not working.
- 5. Repeat this purge sequence for 10 times.
 - a. By doing this, you ensure the residual gas left in the tube is safely diluted.
 - b. At the end of the purge sequence, Switch 3 (N2 Purge) should be off, and Switch 2 (Fast Pump) should be ON.
- 6. Prepare to backfill the tube
 - a. Turn off Switch 2 (Fast Pump)
 - b. Wear solvent gloves. Loosen the ultratorr fitting clockwise about 1-2 turns (no need to fully loosen it all the way)
 - c. Turn on Switch 3 (N2 Purge) to backfill the tube.
 - d. Have your hands on the ultratorr fitting to "feel" it push off the end of the tube. Then, set it aside.
 - e. Turn off Switch 3 (N2 Purge)
 - f. Wear acid gloves. Manipulate your sample pull out boat / put on sample / push in boat
- 7. Take off acid gloves. Reinstall the ultratorr fitting to the quartz tube, and snug down the fitting. Finger tight (counterclockwise) is fine.
- 8. Turn on Switch 1 (Slow Pump)
- 9. Wait for tube to pump down to below <u>1000 mT</u> with the Pirani gauge
- 10. Turn off Switch 1 (Slow Pump)
- 11. Turn on Switch 2 (Fast Pump)
- 12. <u>Run clean process</u>: Clean Recipe must be run after each sulfurization process.
- 13. After completing clean process, decrease plasma power to 0 W, turn off plasma, turn off Ar, and set temperature to 0 $^{\circ}\rm{C}.$
- 14. Keep Switch 2 (Fast Pump) on for 10 minutes, and then turn it off. (Note: Fast pump can be on for more than one day to help reach lower base pressure.)
- 15. Record the base pressure. Should be around 5-20 mTorr (ideally, < 10 mTorr).
- 16. Turn off the vacuum pump with the switch (in the chase).
- 17. Disable the system on iLab.

Tube must be at a low vacuum, with temperature controllers set at 0 °C, and with plasma off before leaving.

After cleaning for 1 hour and overnight pumping, base pressure should be < 10 mTorr. Otherwise, contact staffs.

Recipes:

Clean recipe (must be run after each process)

Temperature	Time	Ar (sccm)	Power
800 °C	1 hour	90	70 W

TaS₂ growth (8 nm)

Temperature	Time	Ar/H ₂ S (sccm)	Power	Metal
400 or 800 °C	20 mins	10/10	70 W	~2-nm Ta

MoS₂ growth (~6 nm)

Temperature	Time	Ar/H ₂ S (sccm)	Power	Metal
400 or 800 °C	20 mins	20/10	70 W	~2-nm Mo